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NO amendment submitted - OK to enter paper - MJP 9/13/04



AFTER FINAL

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

Hyo-sang JUNG

Art Unit: 1762

Serial No. 10/068,005

Examiner: Marianne L. PADGETT

Filed: February 8, 2002

Confirmation No. 6445

For: VACUUM APPARATUS OF ION IMPLANTATION SYSTEM AND EVACUATION METHOD
Atty. Docket No. 262/011

REPLY UNDER 37 C.F.R. § 1.116

Mail Stop AF
Commissioner for Patents
United States Patent and Trademark Office
Alexandria, VA 22313-1450

Sir:

INTRODUCTORY COMMENTS

In response to the Office Action Made Final mailed June 15, 2004, the following remarks are respectfully submitted in connection with the above-identified application.

Remarks begin on page 2 of this paper.